

Photocathode Physics for Photoinjectors (P3) 2016

Monday, October 17, 2016

Semiconductor Manufacture & Measurement: Semiconductor Manufacture & Measurement - F113 Cebaf Center (10:15 AM - 12:15 PM)

-Conveners: Luca Cultrera; John Smedley

time	[id] title	presenter
10:15	[A10] Update of Cornell recent photocathode studies growth and operations	CULTRERA, Luca
10:40	[A11] Study of bialkali antimonide photocathode on niobium substrate at JLab	MAMUN, Md. Abdhulla
10:55	[A12] BNL sputter growth technique	DING, Zihao
11:10	[A13] BNL CHESS Activities	GOAWEI, Mengjia
11:25	[A14] CERN Alkali antimonide experience	HESSLER, Chris
11:50	[A15] DISCUSSION	

Semiconductor Manufacture & Measurement: Semiconductor Manufacture & Measurement - F113 Cebaf Center (1:45 PM - 3:15 PM)

-Conveners: Matt Poelker; Siddharth Karkare

time	[id] title	presenter
1:45 P	[M6] Simultaneous element evaporation and deposition of multialkali cathodes	FENG, Jun
2:00 P	[M8] A Brief Overview of R&D Efforts towards High Quantum Efficiency and High Polarization Superlattice Photocathodes	ZHANG, Shukui
2:15 P	[M9] Ion implantation studies of bulk GaAs with different surface cleave plane orientations	LIU, Wei
2:30 P	[M11] DISCUSSION	